PATENT ABSTRACTS OF JAPAN

(11)Publication number:

09-045691

(43) Date of publication of application: 14.02.1997

(51)Int.CI.

H01L 21/321

(21)Application number : 07-191641

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(22)Date of filing:

27.07.1995

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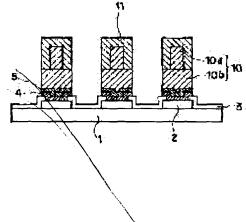
SHIBUYA HITOSHI

(54) SOLDER BUMP FOR CHIP COMPONENT AND ITS MANUFACTURE

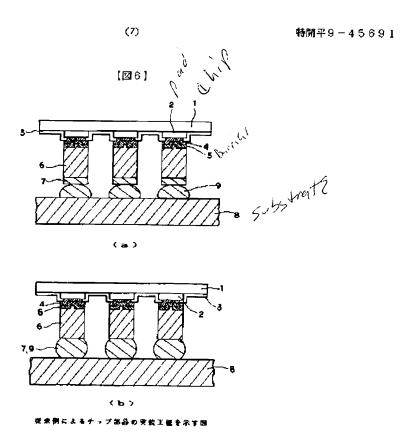
(57)Abstract:

PROBLEM TO BE SOLVED: To provide a solder bump in which the contact area of a first bump with\a second bump is made large and in which their exfoliation at the boundary face between both is prevented by a method wherein the second bump is formed in such a wax that the surface of a large-diameter pillar-shaped part and the circumferential face and the surface of a small-diameter pillar-shaped part are covered with a solder material whose melting point is lower than that of a solder material for the first bump.

SOLUTION: A diffusion-preventing metal film 5 is formed on a carene film 4 formed on an electrode pad 2 while the carene film is used as an electrode for electrolytic plating. A first bump 10 which is formed in a prescribed



height on the diffusion-preventing metal film 5 is composed of a cylindrical large-diameter pillar-shaped part 10b and of a small-diameter pillar-shaped part 10a which is formed on the surface of the large-diameter pillar- shaped part 10b in a diameter which is smaller than that of the large-diameter pillar-shaped part 10b, and both pillar-shaped parts 10a, 10b are formed of the same solder material whose melting point is high. A second bump 11 which is formed in the same diameter as the large- diameter pillar-shaped part 10b so as to cover the surface of the large-diameter pillar-shaped part 10b at the first bump 10 and the circumferential face and the surface of the small- diameter pillar-shaped part 10a is formed of a solder material whose



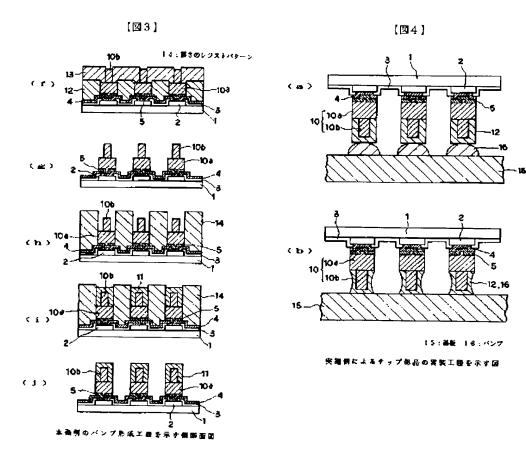
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- 2. **** shows the word which can not be translated.
- 3.In the drawings, any words are not translated.

CLAIMS

[Claim(s)]

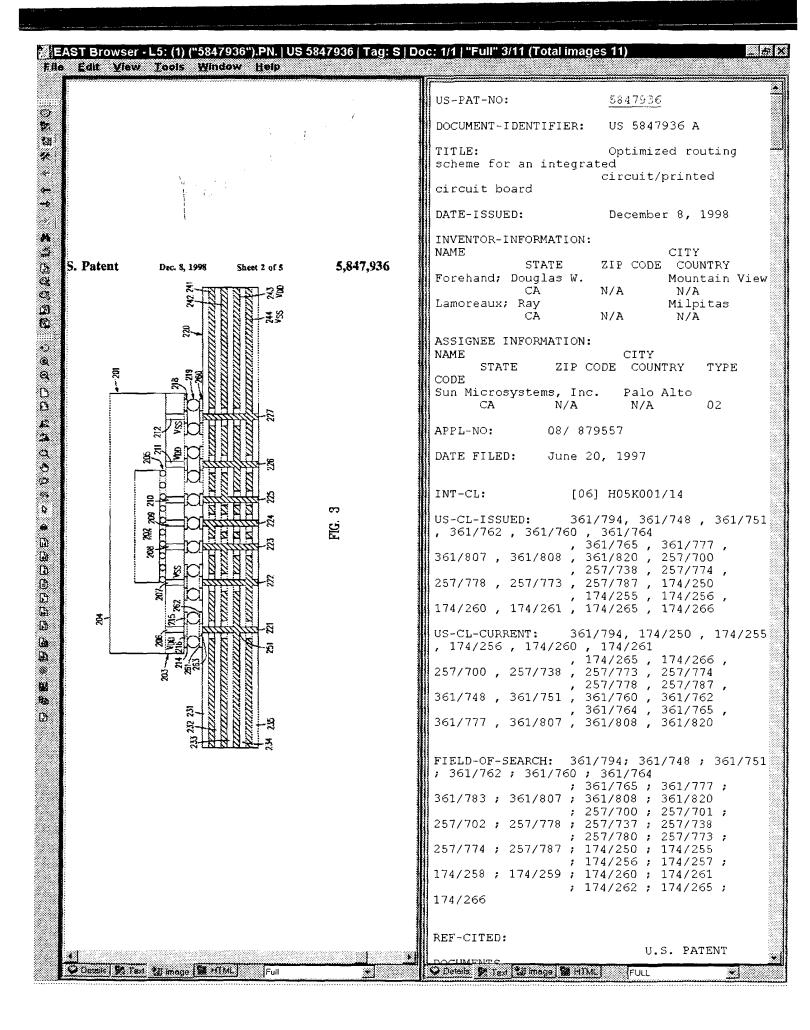
[Claim 1] The major-diameter pillar-shaped section formed of pewter material on the electrode pad of the chip mounted in a substrate, With the 1st bump who consists of this major-diameter pillar-shaped section and the minor diameter pillar-shaped section formed with the path smaller than this major-diameter pillar-shaped section on this major-diameter pillar-shaped section of the same pewter material, and guarantees the height of the chip to the aforementioned substrate So that the melting point may serve as the same path as the aforementioned major-diameter pillar-shaped section from the pewter material of the 1st bump of the above by low pewter material The pewter bump for chips characterized by consisting of the 2nd bump who fuses by heating and makes connection of the aforementioned chip and the aforementioned substrate in case it is formed so that the peripheral surface and the upper surface of the aforementioned minor diameter pillar-shaped section may be covered from the aforementioned major-diameter pillar-shaped section upper surface, and the aforementioned chip is mounted in the aforementioned substrate.

[Claim 2] The 1st resist pattern which has the hole located on the electrode pad of a chip is used as a plating mask. The 2nd resist pattern which has the hole located on this major-diameter pillar-shaped section with a path smaller than the path of this major-diameter pillar-shaped section after forming the major-diameter pillar-shaped section by plating pewter material on the aforementioned electrode pad is used as a plating mask. The minor diameter pillar-shaped section is formed by plating the same pewter material as pewter material on the major-diameter pillar-shaped section. After constituting the 1st bump who consists of the aforementioned major-diameter pillar-shaped section and the minor diameter pillar-shaped section and removing the resist pattern of the above 1st, and the 2nd resist pattern, So that the peripheral surface and the upper surface of the aforementioned minor diameter pillar-shaped section may be covered from the aforementioned major-diameter pillar-shaped section upper surface by using as a plating mask the 3rd resist pattern which has a hole [higher than the 1st bump of the above and] of the same shape as the major-diameter pillar-shaped section The manufacture method of the pewter bump for chips characterized by forming the 2nd bump by plating the low pewter material of the melting point from the aforementioned pewter material.

[Claim 3] The pewter bump for chips characterized by having used as 95% of lead, and 5% of tin composition of the pewter material which forms the 1st pewter bump in the manufacture method of the pewter bump for chips of a claim 1, and a claim 2, and using as 63% of 37% tin of lead composition of the pewter material which forms the 2nd pewter bump, and its manufacture method.

[Claim 4] The pewter bump for chips characterized by having used as 80% of lead, and 20% of tin composition of the pewter material which forms the 1st pewter bump in the manufacture method of the pewter bump for chips of a claim 1, and a claim 2, and using as 63% of 37% tin of lead composition of the pewter material which forms the 2nd pewter bump, and its manufacture method.

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(28)Isolation layer 601 is a dielectric material, for example, a plating mask or a solder mask. Isolation layer 601 is applied using methods well known in the art such as dry film and etching processes, liquid film and photo-imaging processes, IBM's "SLC" process, or other known fabrication techniques.

- (29)Although isolation layer 601 is illustrated in FIGS. 6, 7 and 8, it is understood that step 722 in FIG. 1 is optional and that isolation layer 601 does not have to be formed.
- (30) As represented by block 122 of FIG.
 1, the metallization 502 (FIG. 6) is formed on substrate bonding contact 501C. Metallization 502 can be a multi-metal-layer metallization. embodiment, metallization 502 is formed by applying a copper layer over predetermined portions of substrate bonding contact 501C. Then a nickel layer is selectively applied over the copper layer. Finally a layer of gold or gold alloy is applied over the nickel layer. Generally, the thicknesses of the copper, nickel and gold layers are within the range of 200 micrometers (.mu.m) to 2000 .mu.m, 100 .mu.m to 300 .mu.m and 10 .mu.m to 30 .mu.m, $\,$ respectively.
- In alternative embodiments, metallization 502 is made of, for instance: aluminum; tin over gold over nickel over copper; tin over nickel over copper; lead over gold over tin over aluminum; or tin over lead over gold over tin over aluminum. Metallization 502 is applied using conventional processes such as electroplating or electro-less plating.
- As represented in block 131 of FIG. 1, the substrate is next placed into a standard flip chip fixture such as the Flip Chip Aligner/Bonder available from Research Devices in West Piscataway, N.J. as Part No. M8B. The flip chip fixture includes a heater that can be used, as explained below, to heat the substrate during attachment of the chip.
- As represented by block 132 of FIG. 1, the chip is held in place above the substrate by the flip chip fixture so that the coined ball bond bumps are aligned above corresponding substrate bonding contacts. The substrate is then heated. The chip is aligned with the substrate using a vision system, as is well known in the art. The chip is picked up with a conventional vacuum tool (not shown). The vacuum tool holding the chip can also include an optional heater which heats the chip.

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preferred due to the pointed shape of the resulting coined ball bond bumps 312.

As represented by block 114 of FIG. 1. integrated circuit chips 201 with coined ball boad bumps 312 are separated by using a conventional sawing process. (In an alternative embodiment, the wafer is first sawn into separate chips 201. The good chips, i.e., electrically and physically sound chips. are then separated from the bad chips, Ball bond bumps 202 are then formed on each of the good chips 201 and each of ball bond bumps 202 are coined, as described above, to create coined ball bond bumps 312.)

As described in detail below, each of the chips 201 are then attached to a substrate by contacting coined ball bond bumps 312 to corresponding metallizations on the substrate bonding contacts.

As represented by block 121 of FIG. 1. a substrate is formed for use with the integrated circuit chip to substrate interconnection according to the invention. The substrate is made of any one of various materials such as organic laminate, ceramic, alumina, silicon, printed circuit board. thin film or flexible circuit. In one embodiment, the substrate is created by a printed circuit board process. The substrate can include one or more layers fabricated and interconnected by methods well known by those skilled in the art.

FIG. 6 is a cross-sectional view of substrate 501 showing upper surface 501A, conductive trace 501B, substrate bonding contact 501C, and metallization 502 in accordance with the present invention.

Conductive trace 501B and substrate bonding contact 501C on upper surface 501A of substrate 501 are typically aluminum and are electrically connected to one another. In one embodiment, conductive trace 501B and substrate bonding contact 501C are formed integrally, for example, are formed from the same layer of conductive material. Conductive trace 501B and substrate bonding contact 501C are created by methods well known in the art. It is to be understood that, on the entire substrate 501, there are a plurality of conductive traces 501B and substrate bonding contacts 501C formed on upper surface 501A.

As represented by block 722 of FIG. 1. optionally, an isolation layer 601 (FIG. 6) can be formed over substrate 501 and conductive trace 501B. As shown in FIG. 6. isolation layer 601 is patterned such that isolation layer 601 leaves uncovered a portion of substrate bonding contact 501C. Isolation layer 601 ensures that metallization 502 is applied only to substrate bonding contacts 501C. Isolation layer 601 is particularly useful when the manufacturer wants to conserve the amount of material used in forming metallization 502, such as when metallization 502 includes gold or a gold alloy.

Isolation layer 601 is a dielectric material, for example, a plating mask or a solder mask. Isolation layer 681 is applied using methods well known in the art such as dry film and etching processes, liquid film and photo-imaging processes, IBM's "SLC" process, or other known fabrication techaiques.

Although isolation layer 601 is illustrated in FIGS. 6. 7 and 8. it is understood that step 722 is FIG. 1 is optional and that isolation layer 601 does not have to be formed.

As represented by block 122 of FIG. 1, the metallization 502 (FIG. 6) is formed on substrate bonding contact 501C. Metallization 502 can be a multi-metal-layer metallization. In one embodiment, metallization 502 is formed by applying a copper layer over predetermined portions of substrate bonding contact 501C. Then a nickel layer is selectively applied over the copper layer. Finally a layer of gold or gold

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United States Patent [19]

Pao et al.

(23) Patent Number:

[65] Date of Patent:

5,931,371 Aug. 3, 1999

[54] FIANDOFF CONTROLLED INTERCONNECTION

[75] Inversors: Yt-Hein Pao, Livonia, Chan-Jian Jib. Prov, Jun Ming Hu, Camon, Vivek Annir Jeitzebhoy, Famingson Hills; Richard Kehl McMiller, H. Deutsom, XR Song, Westlend, all of Mich.

[73] Analgare: Ford Motor Company, Beatharn, Mich.

(21) Appl. No.: 88/784,333

[22] Filed: Jan. 16, 1997

[51] Int. CL³ B23K 31/02, B23K 35/24; [52] U.S. Cl 218/160.12; 228/175; 228/145; 561/770; 361/771

[58] Field of Search 278-180.22, 175 228/245; 361/770, 771; 174/138 D

(55) References Cited

U.S. PATENT DOCUMENTS

3,392,447	7/1966	Napir et 41
3,9001:53	6:1975	Beervent et al 228-246
4,402,450		Asaksan et al
1720 945		Spiecker 229/180.2
4.378.611		LaVesco & el
5.035,215		Blanton 29:840
5.093.994		Mandai et ai 25/643
5,147,084		Belien et al
5,251,506		Appresia at al 228/160-27
5,261,593		Cassa et 8:
5,271,548		Materia 226,775
5,323,947		Suake; et al

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OTHER PUBLICATIONS

OTHER PUBLICATIONS

Bruce Chainsts, Principier of Solidification, Alba Wiss and Sons, New York, 1584, pp. 51-152.

"Associated Of Solder Bell Control (SEC) Pselages To Circuit Cartie*, by M.D. Rice et al, BM J. Res. Develop, vol. 37, No. 5, Sep. 1993, pp. 597-668.

"Evaluation of Critical Design Parameters For Surface Mount Leadless Solder Joines Subjected To Thermal Cycling", by Edward the 4st, AMD-vol. 187, Mechanica & Mauriala For Electronic Pselaging: vol. 2-Thormal & Mechanical Belavior & Modeling, ASME 1994, pp. 213-228. 213-228.

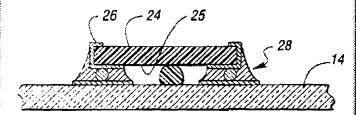
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[57] ABSTRACT

ABSTRACT

A method fiv joining a component to a substrate applies a base unifier portion to the substrate and provides a standard solder portion in the base solder portion. This standard solder portion has a higher neiting temperature than the base solder portion and a height which substrates the solder portion and a height which substrates in the someonest and the advertes to the component and the substrate in a component and the particular portion and the base solder portion is assisted under solder portion and the base solder portion is assisted under reflew combinents to form a solder contribution to the substrate. This joint substrates the same power has the substrate and the substrate. This joint substrates the strategy contains the substrate that the substrate and the

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